

(Title Amended 3/83)

RD-25,90

09/105,783

INFORMATION DISCLOSURE STATEMENT BY APPLICANT--
LIST OF ITEMS

Applicant

RENATO (NMN) GUIDA, ET AL

Filing Date

06/26/98

Group

1756

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JDN	AA 5 5 5 7 6 5 0	09/17/96	GUIDA, ET AL	378	154	09/17/1996
JDN	AB 5 5 8 1 5 9 2	12/03/96	ZARNOCH, ET AL	378	154	12/3/1996
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES No
	AL					
	AM					
	AN					
	AO					
	AP					

OTHER INFORMATION (Including Author, Title, Date, Pertinent pages, Etc.)

JDN	AR	"PHASE MASK MACHINING FOR HIGH THROUGHPUT VIA FORMATION" BY AH SMITH, LITEL INSTRUMENTS, PP 1-6.
JDN	AS	"CYLINDRICAL LENS ARRAYS HOMOGENIZE EXCIMER BEAM" BY B. SMOOTHER, LASER FOCUS WORLD, NOVEMBER 1991, PP 39.
JDN	AT	"APPLICATION OF EXCIMER LASERS IN ELECTRONIC PACKAGING AND MANUFACTURING" BY LAMBDA PHYSIK, 5/96, LAMBDA PHYSIK INDUSTRIAL REPORT, PUBLICATION NO. 10, PP. 1-8.

EXAMINER

Jonathan D. Naugle

DATE CONSIDERED

08/03/1999

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 808; Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.